

IN THE CLAIMS:

This listing of the claims replaces all prior versions and listings of the claims in this application.

The text of all pending claims (including any withdrawn claims) is set forth below. Canceled and not entered claims are indicated with claim number and status only. The claims as listed below show added text with underlining and deleted text with ~~striketrough~~. The status of each claim is indicated with one of (Original), (Currently amended), (Canceled), (Withdrawn), (Previously presented), (New), and (Not entered).

Please AMEND claim 14 and CANCEL claims 1-13 and 20 without prejudice or disclaimer of the subject matter thereof in accordance with the following:

1.-13. (Canceled)

14. (Currently amended) A method of manufacturing an organic EL device, the method comprising:

forming a first electrode layer in a predetermined pattern on an insulating substrate;
forming an organic film comprising at least a patterned emission layer on the first electrode layer;
forming a second electrode layer in a predetermined pattern on the organic film; and
sealing the second electrode layer,
wherein at least one of the organic film and the second electrode layer is deposited using a deposition mask frame assembly, the deposition mask frame assembly comprising:
a mask comprising a thin plate in which a predetermined pattern of apertures is formed,
a frame supporting one surface of the mask so that the mask is tensed, wherein the frame has a flat surface where the frame supports the one surface of the mask, and
a cover mask supporting an opposite surface of the mask, wherein the cover mask corresponds to the frame and has a flat surface where the cover mask supports the opposite surface of the mask;
wherein the frame is flat on at least a side of the frame that supports the one surface of the mask; and

wherein the cover mask is flat on at least a side of the cover mask that supports the opposite surface of the mask.

15. (Original) The method of claim 14, wherein the mask is formed of nickel or an alloy of nickel and cobalt.

16. (Original) The method of claim 14, wherein the mask is formed by electro-forming.

17. (Original) The method of claim 14, wherein the mask, the frame, and the cover mask are joined together by welding.

18. (Original) The method of claim 17, wherein the welding is a dot welding.

19. (Original) The method of claim 18, wherein a welding pitch between welding dots is 3mm or less.

20. (Canceled)